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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/733,217	12/11/2003	Axel Brintzinger	2002 P 12234 US	8003
48154	7590	11/17/2005	EXAMINER	
SLATER & MATSIL LLP 17950 PRESTON ROAD SUITE 1000 DALLAS, TX 75252			THOMAS, TONIAE M	
			ART UNIT	PAPER NUMBER
			2822	

DATE MAILED: 11/17/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary

Application No.

10/733,217

Applicant(s)

BRINTZINGER ET AL.

Examiner

Toniae M. Thomas

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-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 30 August 2005.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-22 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☒ Claim(s) 13-22 is/are allowed.
- 6) ☒ Claim(s) 1-12 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☒ The drawing(s) filed on 11 December 2003 is/are: a) ☒ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
- 1) ☒ Certified copies of the priority documents have been received.
 - 2) ☐ Certified copies of the priority documents have been received in Application No. _____.
 - 3) ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|------------------------------------------------------------------------------------------------------------------------|-----------------------------------------------------------------------------------------|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____ |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | 5) <input type="checkbox"/> Notice of Informal Patent Application (PTO-152) |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

1. This action is responsive to the amendment filed on 30 August 2005.

Currently, claims 1-22 are pending.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

2. Claims 1-12 are rejected under 35 U.S.C. 103(a) as being unpatentable over Miyamoto et al. (US 2002/0093082 A1 in view of Klocke et al. (US 2003/0079989 A1).

The Miyamoto et al. pre-grant published application (Miyamoto) discloses a method of forming a resist layer on a non-planar surface of a substrate (figs. 3, 8, 9, 11-13, 20-22 and pars. 102-121). The method comprises the steps of: providing a substrate 1 having a non-planar surface with protruding 3D structures, wherein the protruding 3D structures comprise passivation layer 3 and photosensitive polyimide layer 5 (fig. 9);¹ and forming a photoresist pattern 8 on the non-planar surface (fig. 12 and par. 110, lines 1-3).

¹ The photosensitive polyimide layer 5 forms a non-planar surface with the top surface of the substrate, wherein the substrate surface up to this step in the process includes the bond pad BP, the passivation layer 3, and the wiring layer 4.

The non-planar surface comprises a substantially planar surface with a structure 5 formed thereon (fig. 9 and par. 108, lines 1-9).

A conductive layer 7 is formed over the non-planar surface prior to forming the photoresist pattern 8, the conductive layer comprising a seed layer (fig. 11 and par. 109, lines 4-10).

A second conductive layer 9 is formed over portions of the seed layer not covered by the photoresist pattern (fig. 12 and par. 110, lines 1-5).

The substrate 1 comprises a semiconductor wafer (par. 102, lines 1-3). In addition, the second conductive layer 9 comprises a reroute layer 2 electrically coupling a contact pad BP formed on the semiconductor wafer to a terminal 14 on the non-planar surface (figs. 3, 22; par. 111, lines 1-5; and par. 121, lines 6-9).²

As explained above, Miyamoto discloses forming a photoresist pattern 8 on the non-planar surface. While Miyamoto discloses forming a photoresist pattern on the non-planar surface, Miyamoto does not disclose forming the photoresist by: placing the non-planar surface into an electrophoretic resist; applying an electrical voltage between the substrate and the electrophoretic resist, while the non-planar surface is in the electrophoretic resist; and removing the non-planar surface from the electrophoretic resist.

The Klocke et al. pre-grant published application (Klocke) discloses a method for depositing an electrophoretic resist on microelectronic workpieces

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for the fabrication of microelectronic devices (par. 9, lines 10-14). The electrophoretic resist is formed by: placing a workpiece into an electrophoretic resist; applying an electrical voltage between the substrate and the electrophoretic resist, while the workpiece is in the electrophoretic resist; and subsequently removing the workpiece from the electrophoretic resist (fig. 17; par. 91, lines 1-19; and par. 111, lines 1-3).

In one embodiment, the method further comprises protecting the rear surface of a workpiece from wetting while the workpiece is placed in the electrophoretic resist (par. 33, lines 12-18 and par. 48, lines 13-19).

In one embodiment, the method further comprises causing the workpiece to be moved relative to the electrophoretic resist while the workpiece is placed in the electrophoretic resist (par. 49, 1-5; par. 51, 1-5; and par. 91, lines 9-19). The workpiece is rotated while the workpiece is placed in the electrophoretic resist (par. 49, 1-5; par. 51, 1-5; and par. 91, lines 9-19).

In one embodiment, the electrophoretic resist is stirred while the workpiece is placed in the electrophoretic resist (par. 49, lines 5-6).

The method further comprises heating the workpiece after removing the workpiece from the electrophoretic resist (par. 112, lines 8-18).

The substrate of Miyamoto has a highly topographical surface. One advantage of using an electrophoretic resist in place of a conventional photoresist is that an electrophoretic resist covers highly topographical

² The reroute layer 2 electrically couples the contact pad BP to the terminal 14 (i.e. solder

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surfaces with a conformal layer of material (Klocke – par. 31, lines 1-6). Thus, it would have been obvious to one of ordinary skill in the art, at the time the invention was made, to modify Miyamoto by using an electrophoretic resist in place of the photoresist, as taught by Klocke, because an electrophoretic resist covers highly topographical surfaces with a conformal layer of material.

3. Claim 6 is rejected under 35 U.S.C. 103(a) as being unpatentable over Miyamoto in view of Klocke as applied to claim 5 above, and further in view of Brooks et al. (US 6,084,297).

As explained above, Miyamoto discloses forming a second conductive layer 9 over portions of the seed layer not covered by the photoresist pattern. While forming the second conductive layer comprises forming a copper layer over portions of the seed layer not covered by the photoresist pattern, and forming a nickel layer over the copper layer (par. 110, lines 6-8), Miyamoto does not disclose forming a gold layer over the nickel layer.

The Brooks et al. patent (Brooks) discloses forming redistribution traces 32 (fig. 1 and col. 5, lines 46-49). The traces comprise a copper layer, a nickel layer formed over the copper layer, and a gold layer formed over the nickel layer (col. 5, lines 50-53).

It would have been obvious to one of ordinary skill in the art, at the time the invention was made, to modify the combination of Miyamoto and Klocke by

bump 14) via bump lands 2A (figs. 3, 22 and par. 121, lines 6-9).

forming a gold layer over the nickel, as taught by Brooks, since triple layer traces comprising gold over nickel over copper are known.

Allowable Subject Matter

4. Claims 13-22 are allowable over the prior art of record.

Response to Arguments

5. Applicant's arguments filed on 30 August 2005 have been fully considered but they are not persuasive.

The Applicant argues that the prior art of record does not teach or suggest the limitations of claim 1 as presented in the amendment filed on 30 August 2005. For reasons discussed above, claim 1 as presented in the amendment filed on 30 August 2005 does not distinguish over the prior art of record. See the rejection above.

The amendment filed on 30 August 2005 has overcome the rejection of claims 14 and 15 under 35 USC 112, second paragraph made of record in the action mailed on 03 June 2005. Accordingly, the rejection has been withdrawn.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Toniae M. Thomas whose telephone number is (571) 272-1846. The examiner can normally be reached on Monday-Thursday from 8:30 a.m. to 5:30 p.m..

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

TMT

14 November 2005



Mary Wilczewski
Primary Examiner